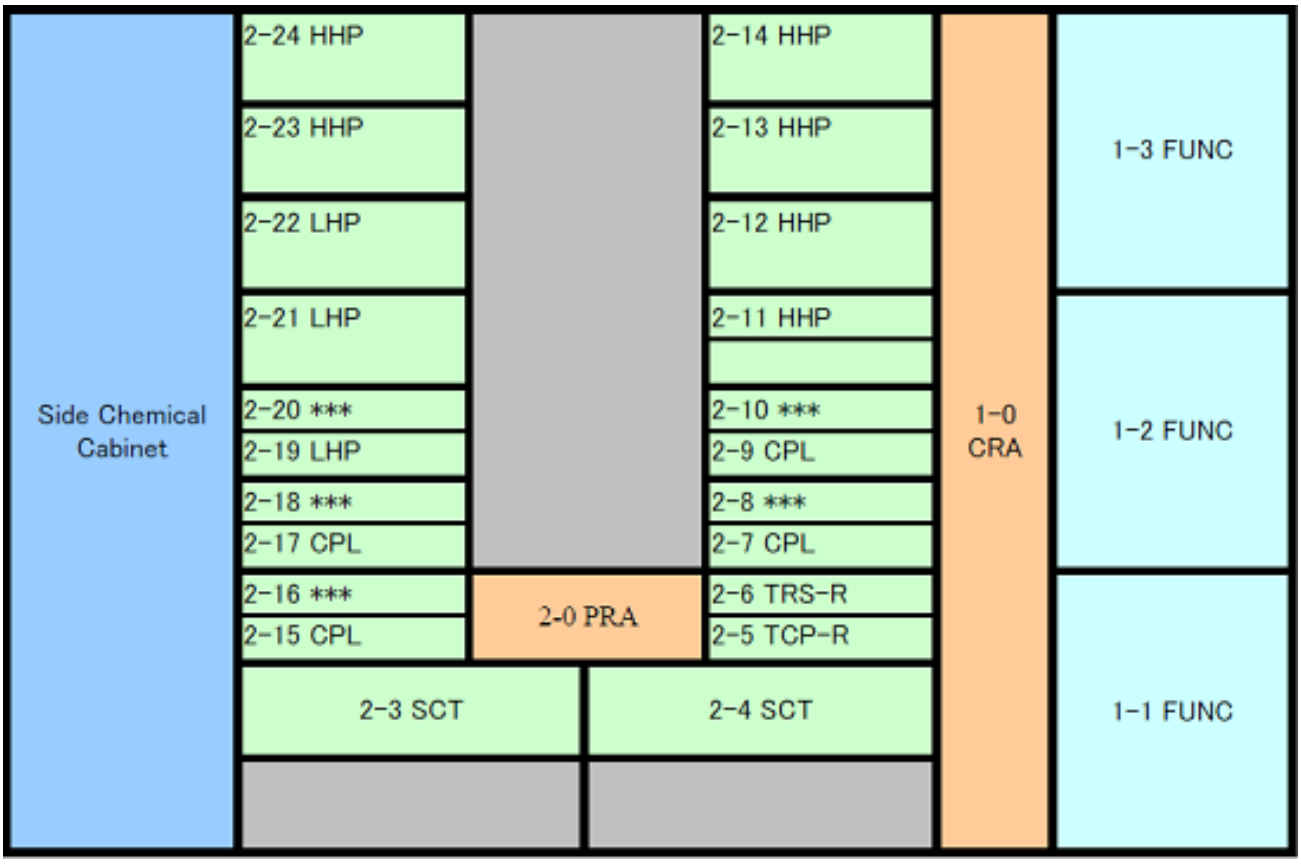
- Manufacturer: Tokyo Electron
- Tool Type: Slam stand-alone Track
- Model: ACT 12
- Wafer Size: 300 mm
- Direction: RIGHT HAND SIDE
- Slam Stand Alone Track
- 2 Wafer Transfer Robot Arms: 1 Carrier, 1 Process
- 3 FOUP Loader Port
- SECS/GEM I/II Interface required is iUSC
- 2 SOG Coater Process Station
  - 2 SOG Nozzles w/ Temperature Control
  - 4 Solvent Capability
  - TARC Compatible: Teflon Coated Chamber
  - PTI Mass Flow Exhaust Controller
  - Temperature Humidity Control
  - 1 Set of SS Back Rinse and Cup Rinse Nozzles
- 4 Chill Plate Process Station
- 1 Transfer Chill Plate Process Station
- 3 Transfer Low Temperature Hot Plate (LHP)
- 6 High Temp Hot Plate Process Stations (HHP)
- 1 TEL Temperature and Humidity Controller
- Side Chemical Cabinet
  - 8 – 2.5 L Bottle Storage Capacity
  - 4 – 2.5 L Bottle Storage Capacity
  - 4 – 12 L Tank Solvent Canisters
- 1 AC Power Box



The tool is right hand side direction.